

Resource Summary Report

Generated by [RRID](#) on Aug 6, 2026

JEOL: BS-80011BPG Plasma Source

RRID:SCR_020158

Type: Tool

Proper Citation

JEOL: BS-80011BPG Plasma Source (RRID:SCR_020158)

Resource Information

URL: <https://www.jeolusa.com/PRODUCTS/Industrial-Equipment/Plasma-Source>

Proper Citation: JEOL: BS-80011BPG Plasma Source (RRID:SCR_020158)

Description: Plasma source that can be used as Ion Plating for thin films, especially optical thin films and with Film quality such as density, adhesion, flatness, index of refraction and absorption are improved by comparison with usual vacuum deposition method

Resource Type: instrument resource

Keywords: Jeol, JEOL, Plasma Source, Instrument Equipment, USEDit,

Availability: Commercially available

Specification URL: https://raw.githubusercontent.com/SciCrunch/RRID-Instruments/main/PDF/SCR_020158.pdf

Resource Name: JEOL: BS-80011BPG Plasma Source

Resource ID: SCR_020158

Alternate IDs: Model_Number_BS-80011BPG

Record Creation Time: 20220129T080348+0000

Record Last Update: 20260801T190652+0000

Ratings and Alerts

No rating or validation information has been found for JEOL: BS-80011BPG Plasma Source.

No alerts have been found for JEOL: BS-80011BPG Plasma Source.

Data and Source Information

Source: [SciCrunch Registry](#)

Usage and Citation Metrics

We have not found any literature mentions for this resource.